



1731

Patent

Docket No.: LWM-A105

Information Disclosure Statement Transmittal

I hereby certify that this transmittal of the below described document is being deposited with the United States Postal Service in an envelope bearing First Class Postage and addressed to the Commissioner of Patents and Trademarks, Washington, D.C., 20231, on the below date of deposit.			
Date of Deposit:	10/04/01	Name of Person Making the Deposit:	Julie Gibson
		Signature of the Person Making the Deposit:	<i>Julie Gibson</i>

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventor(s): Fan Zhong and Jonathan G. Bornstein

Serial No.: 09/874,434

Group Art Unit:

Filed: 06/04/01

Examiner:

Title: METHOD AND SYSTEM FOR A HIGH-DENSITY PLASMA DEPOSITION PROCESS FOR FABRICATING A TOP CLAD FOR PLANAR LIGHTWAVE CIRCUIT DEVICES

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The Commissioner of Patents and Trademarks
Washington, D.C. 20231

Sir:

Information Disclosure Statement Transmittal

Transmitted herewith is the following:

- Formal drawings, totaling sheets.
- Informal drawings, totaling sheets.
- Certification for PTO Consideration
- ☒ Information Disclosure statement (1 sheets)
- Information Disclosure statement and late filing fee
- ☒ Form 1449
- Petition for Extension of Time
- ☒ Other: References

Fee Calculation (for other than a small entity)

Fee Items	Fee Rate	Total
Petition for Extension of Time (fee calculated elsewhere)	\$.00	
Information Disclosure Statement, late filing	\$240.00	
Other:		
Total Fees		

PAYMENT OF FEES

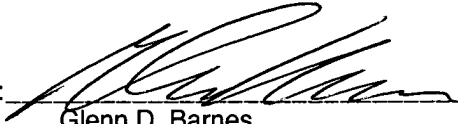
1. The full fee due in connection with this communication is provided as follows:
 - ☒ The Commissioner is hereby authorized to charge any additional fees associated with this communication or credit any overpayment to Deposit Account No.: 23-0085.
A duplicate copy of this authorization is enclosed.
 - ☐ A check in the amount of \$
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Please direct all correspondence concerning the above-identified application to the following address:

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Respectfully submitted,

Date: 10/4/01

By: 
Glenn D. Barnes
Reg. No. 42,293



Attorney Docket No.: LWM-A105

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE
Patent Application

Inventor(s): Fan Zhong and Jonathan G. Bornstein Group Art Unit:

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Form 1449

U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class	Filing Date
	A	5,904,491	05/18/99	Ojha	438	31	04/23/97
	B	5,991,487	11/23/99	Sugiyama	385	129	09/22/97
	C	6,108,480	08/22/00	Mizuta	385	129	07/28/99
	D	5,978,539	11/02/99	Davies	385	129	10/03/97
	E	6,002,823	12/14/99	Chandross	385	50	08/05/98
	F	5,500,916	03/19/96	Cirelli	385	37	09/09/94
	G	4,851,025	07/25/89	Siefert	65	31	12/02/87
	H	4,934,774	06/19/90	Kalnitsky	350	96.12	06/08/89
	I	5,408,569	04/18/95	Nishimoto	385	132	03/21/94
	J	4,045,198	08/30/77	Rau	65	33	08/24/76
	K	4,242,118	12/30/80	Irven	65	3	04/27/79

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Publication Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
	L							
	M							
	N							
	O							
	P							
	Q							

Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
	R	
	S	
	T	
Examiner		Date Considered

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.